Application No.: 10/817,611
Applicant: Sheng Sun et al.
Title: METHOD AND SYSTEM FOR CONTROL OF PROCESSING
CONDITIONS IN PLASMA PROCESSING SYSTEMS
Replacement Drawings Sheet 1 of 11

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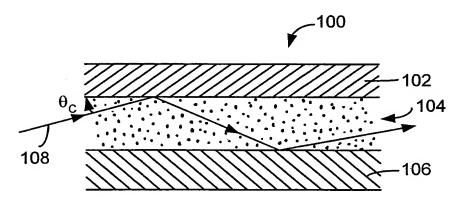


FIG. 1A PRIOR ART

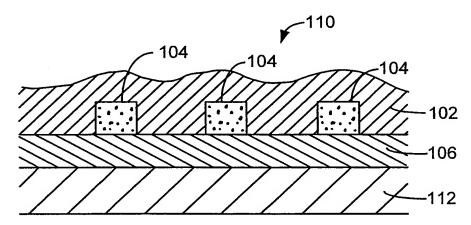


FIG. 1B PRIOR ART